

# Chen Wang

## List of Publications by Year in descending order

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32  
papers

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citations

1040056

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h-index

888059

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all docs

32  
docs citations

32  
times ranked

217  
citing authors

#	ARTICLE	IF	CITATIONS
1	On the Dynamic Range and Resolution of Thermal-Piezoresistive Resonant Mass Sensors. Journal of Microelectromechanical Systems, 2022, 31, 180-182.	2.5	1
2	A Gas Sensor Based on Zif-8-Coated Coupled Resonators With Enhanced Sensitivity and Reversible Detection Ability. , 2022, , .		1
3	Correlated Theory of Cross-Axis Interference of MEMS Devices Based on Parallel Plate and Squeeze Film Air Damping Induced Suppression. IEEE Sensors Journal, 2022, 22, 6698-6705.	4.7	0
4	A Resonant Lorentz-Force Magnetometer Exploiting Blue Sideband Actuation to Enhance Sensitivity and Resolution. Journal of Microelectromechanical Systems, 2022, 31, 402-407.	2.5	4
5	Accurate mechanical“optical theoretical model of cross-axis sensitivity of an interferometric micro-optomechanical accelerometer. Applied Optics, 2022, 61, 3201.	1.8	0
6	Python-Based Open-Source Electro-Mechanical Co-Optimization System for MEMS Inertial Sensors. Micromachines, 2022, 13, 1.	2.9	10
7	A Review on Coupled Bulk Acoustic Wave MEMS Resonators. Sensors, 2022, 22, 3857.	3.8	12
8	Genetic Algorithm for the Design of Freeform Geometries in a Large-Range Rotary Microgripper. , 2021, , .		1
9	Towards a Hybrid Mass Sensing System by Combining a QCM Mass Sensor With a 3-DOF Mode Localized Coupled Resonator Stiffness Sensor. IEEE Sensors Journal, 2021, 21, 8988-8997.	4.7	4
10	Investigation of the Influence of Temperature and Humidity on the Bandwidth of an Accelerometer. Micromachines, 2021, 12, 860.	2.9	1
11	Investigation of a complete squeeze-film damping model for MEMS devices. Microsystems and Nanoengineering, 2021, 7, 54.	7.0	17
12	A Resonant Lorentz-Force Magnetometer Featuring Slotted Double-Ended Tuning Fork Capable of Operating in a Bias Magnetic Field. Journal of Microelectromechanical Systems, 2021, 30, 958-967.	2.5	7
13	Micromachined Accelerometers with Sub- $\mu\text{g}/\text{s}^2\text{Hz}$ Noise Floor: A Review. Sensors, 2020, 20, 4054.	3.8	56
14	Electro-Mechanical Co-optimization of MEMS Devices in Python. , 2020, , .		0
15	Modal-based nonlinear optimization algorithm for wavefront measurement with under-sampled data. Optics Letters, 2020, 45, 5456.	3.3	7
16	Genetic algorithm for electro-mechanical co-optimization of a MEMS accelerometer comprising a mechanical motion pre-amplifier with a 2nd-order sigma delta modulator. , 2019, , .		1
17	A Novel Qcm Mass Sensing System Incorporated with A 3-Dof Mode Localized Coupled Resonator Stiffness Sensor. , 2019, , .		3
18	Genetic Algorithm for the Design of Freeform Geometries in a MEMS Accelerometer Comprising a Mechanical Motion Pre-Amplifier. , 2019, , .		4

#	ARTICLE	IF	CITATIONS
19	Description of complex optical surface based on sparse radial basis function approximation with spatially variable shape parameters. , 2019, , .		1
20	Unconstrained self-calibration of stereo camera on visually impaired assistance devices. Applied Optics, 2019, 58, 6377.	1.8	6
21	Single Chip-Based Nano-Optomechanical Accelerometer Based on Subwavelength Grating Pair and Rotated Serpentine Springs. Sensors, 2018, 18, 2036.	3.8	15
22	A mass sensor based on 3-DOF mode localized coupled resonator under atmospheric pressure. Sensors and Actuators A: Physical, 2018, 279, 254-262.	4.1	42
23	A Reversible Method to Characterize the Mass Sensitivity of a 3-Dof Mode Localized Coupled Resonator under Atmospheric Pressure. Proceedings (mdpi), 2017, 1, 493.	0.2	5
24	Comparison of two panoramic front unit arrangements in design of a super wide angle panoramic annular lens. Applied Optics, 2016, 55, 3219.	1.8	20
25	Minimizing cross-axis sensitivity in grating-based optomechanical accelerometers. Optics Express, 2016, 24, 9094.	3.4	40
26	Tolerance analysis of the pulse signal of a novel lateral deformable optical NEMS grating transducer. , 2015, , .		0
27	Highly sensitive lateral deformable optical MEMS displacement sensor: anomalous diffraction studied by rigorous coupled-wave analysis. Applied Optics, 2015, 54, 8935.	2.1	2
28	Photolithography using lateral surface of nanofibers. Optics Communications, 2015, 343, 195-200.	2.1	1
29	Subnanometer resolution displacement sensor based on a grating interferometric cavity with intensity compensation and phase modulation. Applied Optics, 2015, 54, 4188.	2.1	34
30	Tolerance analysis and optimization of a lateral deformable NEMS zeroth-order gratings. Optics Communications, 2015, 355, 356-366.	2.1	4
31	A MOEMS Accelerometer Based on Diffraction Grating with Improved Mechanical Structure. International Journal of Automation Technology, 2015, 9, 473-481.	1.0	3
32	Focused laser lithographic system with sub-wavelength resolution based on vortex laser induced opacity of photochromic material. Optics Letters, 2014, 39, 6707.	3.3	5